ALD 2018 - 18th International Conference on Atomic Layer Deposition

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Title	ALD 2018 - 18th International Conference on Atomic Layer Deposition
When	So, 29. Juli 2018 - Mi, 1. August 2018

Description

ALD 2018 - 18th International Conference on Atomic Layer Deposition

The AVS 18th International Conference on Atomic Layer Deposition (ALD 2018) featuring the 5th International Atomic Layer Etching Workshop (ALE 2018) will be a three-day meeting dedicated to the science and technology of atomic layer controlled deposition of thin films and now topics related to atomic layer etching.

The conference will take place Sunday, July 29-Wednesday, August 1, 2018, at the Songdo Convensia in Incheon, South Korea.

Please find more information on following website:

https://ald2018.avs.org/

Venue - Songdo Convensia in Incheon

Location	Songdo Convensia in Incheon
City	Incheon
Country	KR